



**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the application of	)	
	)	
Topas CHANG et al.	)	Group Art Unit: 2125
	)	
Application No. 10/775,595	)	Examiner: J. Gandhi
	)	
Filed: February 9, 2004	)	Attorney Docket No. MXICP016
	)	
For: SYSTEM AND METHOD FOR	)	Date: January 26, 2006
MONITORING WAFER FURNACE	)	
PRODUCTION EFFICIENCY	)	Confirmation No. 1768
	)	

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on January 26, 2006.

Signed: \_\_\_\_\_

Diane Schwanbeck

**AMENDMENT**

Commissioner for Patents  
Post Office Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Applicants submit this paper in response to the Office Action dated July 26, 2005. A response to this Office Action was due on October 26, 2005. Accordingly, Applicants are concurrently submitting a request for a three-month extension of the period for response.

Please amend this application as follows:

The **Amendments to the Specification** begin on page 2 of this paper.

The **Amendments to the Claims** made herein are reflected in the **Listing of Claims**, which begins on page 3 of this paper.

The **Amendments to the Drawings** are shown on page 6 of this paper and include four (4) sheets of replacement drawings.

Applicants' **Remarks** begin on page 7 of this paper.